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## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*\*

This appln claims benefit of 60/472,468 05/22/2003

*verified sp*

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

EUROPEAN PATENT OFFICE (EPO) 02293049.9 12/10/2002

EUROPEAN PATENT OFFICE (EPO) 03292888.9 11/20/2003

*verified sp*

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 03/18/2004

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY FRANCE	SHEETS DRAWING 3	TOTAL CLAIMS 23	INDEPENDENT CLAIMS 1
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged Examiner's Signature <i>[Signature]</i> Initials <i>EF</i>				

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## TITLE

Two-stage annealing method for manufacturing semiconductor substrates

FILING FEE	FEES: Authority has been given in Paper	<input type="checkbox"/> All Fees
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